

### Integrated Modeling Toolset for ECR Charge Breeder Ion Sources \* – MCBC, GEM, IonEx

## J.S. Kim, B. Cluggish, L. Zhao, S. Galkin, L. Grubert and E. Evstati

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FAR-TECH, Inc., 3550 General Atomics Court, MS 15-155, San Diego, CA 92121 Tel: (858) 455-6655, Fax (858) 450-9741 www.far-tech.com

## FAR –TECH, Inc.

The name FAR stands for Fusion and Accelerator Research

Founded in 1994, located in San Diego, CA

•Core staff: 12 PhD physicists/engineers + 1 admin

•Core technology: electromagnetism (hardware and software)

- Accelerator technology ( custom orders received/delivere)
  - •RF sources
  - •RF structure/components
  - System integration
  - •Modeling and simulation
- •Plasma science and technology











#### PBGUNS: (Particle Beam gun simulation) code lon trajectories, J(r) and emittance



#### **FAR-TECH** has Meshless computing technology

Adaptive computation – multi scale problem Easy to handle complex geometry Petascale computing







#### Integrated Modeling Toolset for ECR Charge Breeder Ion Sources

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#### **Motivation and Introduction**



#### High charged ion beams, in particular Rare Isotope Beams (RIBs), are needed for Nuclear Physics studies and have industrial applications



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Taken from www.CPEPweb.org

#### Rare Isotope beam (RIB) facilities in US and worldwide

- US RIB Nuclear Physics facilities, such as
  - Facility for Rare Isotope Beams (FRIB) at Michigan State University
  - ATLAS CAlifornium Rare Isotope Breeder Upgrade (CARIBU) at Argonne
  - Cyclotron Institute at Texas A&M
  - Holifield Radioactive Ion Beam Facility (HRIBF) at ORNL
- Worldwide RIB Nuclear Physics facilities, such as
  - SPIRAL2 (GANIL, France)
  - ISOLDE (CERN)
  - Triumph (Canada)
  - KEK (Japan)
  - ...



#### An efficient way to produce high charge RIBs is by Electron-Cyclotron-Resonance (ECR) Charge-Breeder (CB).



- 1+ beam is injected and trapped in a mirror confined plasma
- The plasma is produced/sustained through ECR heating with microwave power
- Trapped ions are bred to high charge state through electron impact ionization
- Highly charged ions are extracted and selected by desired charge/mass ratio



**RIBs and next generation ECRIS are expensive.** 

Modeling can minimize trial and error optimization experimental and design costs.

The Project Goal was to develop a charge breeder simulation toolset



#### ECR CB is complex and Modeling is difficult



- ECR CB modeling must integrate ion injection, ionization, and extraction.
- ECR Plasma modeling involves multiple physical processes
- Many ion charge states must be followed
- Extraction region involves multiple spatial scales;

must resolve plasma meniscus.



#### **FAR-TECH's modeling strategy**

- Full particle based (particle-in-cell) modeling is not practical
  - 10<sup>11</sup> time steps for accurate simulation of ECR heating to steady state
  - Total number of floating point operations

 $= N_{step} \times N_{flop} \times N_{p} = 10^{11} \times 10^{3} \times 10^{9} = 10^{23}$ 

- Even with petaflops, total time for 1 run requires  $10^{23}/10^{15} = 10^8 \text{ s} = 3.2 \text{ years}$
- Instead, plasma is modeled with much faster continuum method
  - Bounce-averaged Fokker-Planck for electrons
  - Fluid model for ions
  - Time step can be larger than PIC by10<sup>6</sup>
- Use particles only for incoming and outgoing beams
- Adaptive meshfree computation to resolve multi-scale spatial problem with plasma sheath (meniscus) << 1 mm << device length of 30 cm</li>



#### Modeling is still challenging!

- Multiple species (e.g. 18 charge states for Ar, 37 for Rb)
- Ionization, charge-exchange cross sections not well known
- Coulomb collisions play crucial role
  - Long range force
  - Determine electron confinement time
- Strong gradients within plasma
  - Electron "temperature" ranges from 10 to 10,000 eV
  - Electron density ranges from 10<sup>14</sup> to 10<sup>18</sup> m<sup>-3</sup>



## ECR Charge Breeder is modeled in three modules, each representing distinctive physical process.



Monte Carlo Beam Code Beam injection and slowing down into an ECR plasma



## ECR Charge Breeder is modeled in three modules, each representing distinctive physical process.



#### MCBC

Monte Carlo Beam Code Beam injection and slowing down into an ECR plasma

#### GEM

#### **Generalized ECRIS Modeling**

- Models ECR heated plasma confined in a magnetic mirror machine
- Calculates charge state distribution and profiles of plasma ions and injected ions

#### IonEx

Ion extraction Extraction of an ion beam from an ECRIS

# Each code includes considerable physics and computational techniques (See our publication for details). Next, we simply present an example.

**Publication list:** 

- Jin-Soo Kim, Liangji Zhao, Brian Cluggish, Sergei Galkin, Liz Grubert, "Integrated Modeling of ECR Ion Source and Charge Breeders with GEM, MCBC, and IonEx," Rev. Sci. Instrum. 81, 02A905 (2010)
- S. A. Galkin, J. E. Grubert, B. P. Cluggish, N. Barov, J. S. Kim, "IonEx A Meshfree Ion Extraction Code based on PICOP," Review of Scientific Instruments, Vol. 81, Issue 2, 02B705 (2010).
- L. Zhao, B. Cluggish, J. S. Kim, R. Pardo, and R. Vondrasek, "Simulation of charge breeding of rubidium using Monte Carlo charge breeding code and generalized ECRIS model," Rev. Sci. Instrum. 81, 02A304 (2010)
- B. P. Cluggish, L. Zhao, and J. S. Kim, "Simulation of Parameter Scaling in ECR Ion Source Plasmas using the GEM code," Rev. Sci. Instrum. 81, 02A301 (2010)
- B. P. Cluggish, L. Zhao, and J. S. Kim, "Modeling of the Stability of Electron Cyclotron Resonance Ion Source Plasmas," submitted to Nucl. Inst. Method.
- S. A. Galkin, J. E. Grubert, B. P. Cluggish, J. S. Kim, S. Yu Medvedev, "3D Hybrid Meshless Adaptive Algorithm and Code for Ion Extraction Problem ", ICOPS Meeting, May 31 June 5 2009, San Diego, Ca
- L. Zhao, J. S. Kim, and B. Cluggish, "Validation and Application of GEM (General ECRIS Modeling)", Proc. of the 23rd Particle Accelerator Conference, Vancouver, Canada, 2009.
- L. Grubert, N. Barov, B. Cluggish, S. Galkin, and J.S. Kim, "Graphical Front-End and Object-Oriented Design for IonEx, an Ion Extraction Modeling Code", Proc. of the 23rd Particle Accelerator Conference, Vancouver, Canada, 2009.
- J.S. Kim, L. Zhao, B. P. Cluggish, I. N. Bogatu, S. Galkin, and L. Grubert, "Status of FAR-TECH's Electron-Cyclotron-Resonance Charge-Breeder Simulation Toolset: MCBC GEM and IonEx", Proc. of the 18th annual workshop on ECR Ion Sources, Chicago, IL USA, pp. 156-159, (2008).
- S. A. Galkin, B. P. Cluggish, J. S. Kim, S. Yu. Medvedev "Advanced PICOP Algorithm with Adaptive Meshless Field Solver", Published in the IEEE PPPS/ICOP 2007 Conf. proc., (2007) pp. 1445-1448.
- B. P. Cluggish, S. A. Galkin, and J. S. Kim, "Modeling Ion Extraction from an ECR Ion Source," Proceeding of the 2007 Particle Accelerator Conference, Albuquerque, NM, June 25-29, 2007
- J. S. Kim, I. N. Bogatu, B. P. Cluggish, S. A. Galkin, L. Zhao, R. C. Pardo, and V. Tangri, "Status of FAR-TECH's ECR Ion Source Optimization Modeling," Proceeding of the 2007 Particle Accelerator Conference, Albuquerque, NM, June 25-29, 2007



## ECR CB Example

#### Using MCBC, GEM and IonEx for ANL ECRCB for Rb+ beam into oxygen plasma



| Device Leverth                           | 00                  |              |                 |
|--|---------------------|--------------|-----------------|
| Device Length                            | 29 cm               | rf Frequency | 10.44 GHZ       |
| Device Radius                            | 4 cm                | rf Power     | 70 W            |
| B <sub>iniection</sub> /B <sub>min</sub> | 1.16T / 0.27T = 4.3 | Plasma lons  | oxygen          |
| Bextraction/Bmin                         | 0.83T /0.27T = 3.1  | Gas Pressure | 0.12 micro-torr |

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#### **Generalized ECRIS Modeling**

# Obtain a steady state of background plasma with GEM



#### **GEM 2D (r,z) simulation**

# Steady state background oxygen plasma shows hollow electron density and temperature profiles, due to hollow Electron Cyclotron Resonance (ECR) region







## MCBC

#### Monte Carlo Beam Code

MCBC tacks beam ions in plasma.



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Movie shows single Rb+ beam ion trajectory simulated by MCBC. As the ion traverses in the plasma longer, it becomes more highly charged (color coded) by electron impact.



Tracking all the injected beam ions until extraction is computationally expensive



Instead, we compute MCBC until injected ions are pass through, lost to walls or slowed-down to thermal speed of the background plasma ion ("captured").

Then utilize the captured profiles as input source profiles for GEM.







#### **Generalized ECRIS Modeling**

#### Repeat Step 1, including ion sources from the captured Rb+1, +2, +3, ... to GEM



#### Steady state profiles of electron density and Rb ions



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#### **Ion Extraction Modeling Code**

#### Adaptive meshfree code





## GEM 2D (r,z) simulated steady state profiles of $n_e(r)$ , $T_e(r)$ , J(r) at extraction are the inputs to IonEx





#### **IonEx** simulation



J(r) for all oxygen ions (+1 thru +8) at z=0 and 2.8 cm

1.8

1.6

1.4

1.2

0.8

0.6-

0.4

0.2

0-

0

0.001

0.002

radius (m)

0.003

0.004

0.005

current density (A/m $^{\circ}$ 2)

Emittance at z = 2.8 cm





0 0.002 0.004 0.006 0.008 0.01

radius (m)

0.012 0.014 0.016

0.8

0.7

0.6-

0.5

0.4

0.3

0.2

0.1

0-

current density (A/m^2)

#### **IonEx Simulations:**





J(r) for all Rb ions (+1 thru +25) at z=0 and 2.8 cm









r

#### IonEx benchmarked with PBGUNS: Trajectories, J(r) and emittance



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## **Summary** End-to-End Integration of ECR Charge Breeder Modeling underway

FAR-TECH's Suite of Codes for ECR Charge Breeder Modeling

| MCBC | GEM | lonEx |
|------|-----|-------|
|------|-----|-------|

Full 3d3v Atomic data Coulomb collisions 2d2v Fluid Ions Fokker-Plank Electrons (bounce averaged) Coulomb collisions Atomic collisions Adaptive meshfree Multi-species



## FAR-TECH's ECRCB modeling toolset begins to provide guidance on ECRCB / ECRIS

- It has provided better understanding of ECRIS plasma and ECRCB through plasma physics and computation.
   – one of the few modeling efforts in the world
- It is the first ECRCB simulation toolset that models from injection to extraction in an integrated manner.
- Integrated modeling provides parameter dependence.
  Optimum injected beam energy for target charge states



#### **GUI** controls the integration of MCBC, GEM, and IonEx.



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#### **Future plan**

- The Phase II project ended in Aug 2010.
- Distribution of full executables is still far away.
  - It is best for us to run our codes due to complexity and difficulty of the problem
- Technical support to RIB and ECRIS laboratories is feasible.
- Still much to improve to support ECR CB in an efficient manner! We have plans for improving our models / codes
  - physics model to include 3D mirror fields
  - more robust computational algorithms



# Thanks for Listening and Support

